



3723P

## PATENT

Attorney Docket No. A-70092/RMA/JML (469090-14)

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  KAJIWARA, et al.	Examiner: MORGAN, EILEEN P  Group Art Unit: 3723	
Serial No.: 09/874,174	<u>CERTIFICATE OF MAILING</u>	
Filing Date: 4 JUNE 2001	I hereby certify that this correspondence and its listed enclosures is being deposited with the United States Postal Service as First Class Mail addressed to Commissioner for Patents; P.O. Box 1450; Alexandria, VA 22313-1450 on April 9, 2004.	
For: <b>CHEMICAL MECHANICAL POLISHING APPARATUS AND METHOD HAVING A RETAINING RING WITH A CONTOURED SURFACE</b>	Signed  Wendy Wilson	

## AMENDMENT

RECEIVED

APR 20 2004

TECHNOLOGY CENTER 3700

Sir:

Following is Applicants' response to the Restriction Requirement mailed 11 February 2004. The response is accompanied by a petition for a one-month extension of time and the requisite fee. A response is therefore due 11 April 2004, making this a timely response. Applicant hereby elects the claims associated with Group 1 (claims 1-3, 5, 7-20, 25-33, and 41) for further prosecution at this time. The election is made without traverse.

Please amend the application as indicated on the following pages, and consider the remarks herein. While Applicant believes that no further fees are due at this time, the Commissioner is authorized to charge any fees that may be due as a result of filing this amendment, including additional claims fees not already paid for, or other fees that have not been separately paid, to Deposit Account 50-2319 (Order No. A-70092/RMA/JML (469090-14)).

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